

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Truskett, Van N.
Appl. No.: 10/687,519 GPAU.: 1762
Filed: October 16, 2003 Examiner: Bret P. Chen
Docket No.: P75-17-03 Conf. No.: 5222
For: LOW SURFACE ENERGY TEMPLATES

INFORMATION DISCLOSURE STATEMENT

Mail Stop AMENDMENT
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

The following information is submitted in compliance with Applicants' duty of disclosure and pursuant to 37 C.F.R. § 1.56, § 1.97 and § 1.98. The undersigned brings the patents, publications, applications or other information identified in the attached:

☒ Form(s) PTO/SB/08A and/or PTO/SB/08B or PTO/1449

to the Examiner's attention in the above-identified application.

It is respectfully requested that the cited information be expressly considered during the prosecution of this application, and the references be made of record therein and appear among the "references cited" on any patent to issue therefrom.

Applicants note that on an Information Disclosure Statement [hereinafter IDS1] filed on 20 November 2004 and received by the United States Patent and Trademark Office [hereinafter USPTO] on 26 November 2004, references D247, D249, D250, D278-D280, D301, D312-D319, D323, D325, and D326 [hereinafter REFS] were crossed off. Further, Applicants note that on IDS1 proximate to REFS, the words "NOT PUBLIC" appear. To that end, Applicants assume REFS were crossed off for allegedly containing serial numbers of United States patent applications filed with the USPTO.

Information Disclosure Statement

App. No. 10/687,519

Page 2 of 2

Referring to 37 CFR § 1.98(a) it is stated "[a]ny information disclosure statement filed under [37 CFR] § 1.97 shall include...[a] list of all patents, publications, applications, or other information submitted for consideration by the Office." Further, referring to 37 CFR §1.98(b)(3) it is stated "[e]ach U.S. application listed in an information disclosure statement must be identified by the inventor, application number, and filing date."

To that end, Applicants respectfully contend that REFS comport with the requirements of 37 CFR § 1.98(b)(3). Applicants submit here with a Supplemental Information Disclosure Statement [hereinafter SUPP IDS1] having REFS listed thereon. More specifically, references D247, D249, D250, D278-D280, D312-D314, D316-D318, D325, and D326 of IDS1 are cited as references J1, J2, J3, J4-J6, J7-J9, J11-J13, J14, and J15 of SUPP IDS1 respectively, now United States patent application publications; references D301 and D323 of IDS1 are cited as references J16 and J17 of SUPP IDS1; and reference D315 of IDS1 is cited as reference J10 of SUPP IDS1, now a United States patent.

Applicant does not believe that any additional fees are due, but if the Commissioner believes additional fees are due,. The Commissioner is hereby authorized to charge requisite fees, or credit any overpayment, to Deposit Account Number 502650.

CERTIFICATE OF TRANSMISSION/MAILING

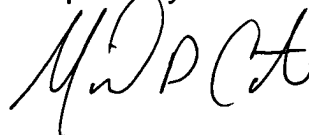
I hereby certify that this correspondence is being facsimile transmitted to the USPTO or deposited with the United States Postal Service with sufficient postage as first class mail, in an envelope addressed to the Commissioner for Patents.

Signed: 

Typed Name: Jennifer L. Cowlshaw

Date: 02/03/2006

Respectfully Submitted,



Michael D. Carter

Reg. No. 56,661

Registered Patent Agent

Legal Department

Molecular Imprints, Inc.

P.O. Box 81536

Austin, Texas 78708-1536

Telephone: 512-339-7760

Facsimile: 512-491-8918

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**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

(Use as many sheets as necessary)

Complete if Known

Application Number	10/687,519
Filing Date	10/16/2003
First Named Inventor	Truskett et al.
Art Unit	1762
Examiner Name	Chen, Bret P.
Attorney Docket Number	P75-17-03

Sheet 1 of 2

U. S. PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number-Kind Code ² (if known)			
	J1	US- 2005/0064344-A1	3/24/2005	Bailey et al.	
	J2	US- 2005/0082253-A1	4/21/2005	Cherala et al.	
	J3	US- 2005/0051698-A1	3/10/2005	Sreenivasan et al.	
	J4	US- 2005/0074512-A1	4/7/2005	McMackin et al.	
	J5	US- 2005/0072757-A1	4/7/2005	McMackin et al.	
	J6	US- 2005/0072755-A1	4/7/2005	McMackin et al.	
	J7	US- 2004/0170770-A1	9/2/2004	Nguyen et al.	
	J8	US- 2004/0256764-A1	12/23/2004	Choi et al.	
	J9	US- 2004/0146792-A1	7/29/2004	Nimmakayala et al.	
	J10	US- 6,955,868-B2	10/18/2005	Choi et al.	
	J11	US- 2005/0189676-A1	9/1/2005	Sreenivasan	
	J12	US- 2004/0251775-A1	12/16/2004	Choi et al.	
	J13	US- 2004/0124566-A1	7/1/2004	Sreenivasan et al.	
	J14	US- 2005/0187339-A1	8/25/2005	Xu et al.	
	J15	US- 2005/0100830-A1	5/12/2005	Xu et al.	
		US-			
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		US-			

FOREIGN PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	Foreign Patent Document	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages Or Relevant Figures Appear	T ⁶
		Country Code ³ Number ⁴ Kind Code ⁵ (if known)				

Examiner
SignatureDate
Considered

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This collection of information is required by 37 CFR 1.97 and 1.98. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This collection is estimated to take 2 hours to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND

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Application Number 10/687,519

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First Named Inventor Truskett et al.

Art Unit 1762

Examiner Name Chen, Bret P.

Attorney Docket Number P75-17-03

Sheet

2

of

2

NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
	J16	Sreenivasan et al., "An Imprint Lithography System to Produce a Light to Impinge upon and Polymerize a Liquid in Superimposition with Template Overlay Marks," U.S. Patent Application 10/864,214, filed with USPTO June 9, 2004	
	J17	Willson et al., "Step and Flash Imprint Lithography," U.S. Patent Application 10/806,051, filed with UPSTO March 22, 2004	

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☐ Other:


to the Examiner's attention in the above-identified application. It is respectfully requested that the cited information be expressly considered during the prosecution of this application, and the references be made of record therein and appear among the "references cited" on any patent to issue therefrom.

This Information Disclosure Statement is being filed during the period specified in § 1.97(c). Accordingly, the fee set forth in § 1.17(p) is required and provided as shown below.

The Commissioner is hereby authorized to charge \$180.00 for submission of the Information Disclosure statement per 1.17(p); plus any other fees which may be required, or credit any overpayment, to Deposit Account Number 502650.

CERTIFICATE OF TRANSMISSION/MAILING

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Substitute for form 1449A/PTO

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Sheet

1

of

4

Application Number

10/687,519

Filing Date

10/16/2003

First Named Inventor

Truskett et al.

Group Art Unit

1762

Examiner Name _____

Chen, Bret P.

Attorney Docket Number

P75-17-03

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Sheet

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Complete if Known

Application Number	10/687,519
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Filing Date	10/16/2003
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First Named Inventor	Truskett et al.
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Group Art Unit	1762
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Examiner Name	Chen, Bret P.
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Attorney Docket Number	P75-17-03
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FOREIGN PATENT DOCUMENTS

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¹Unique citation designation number. ²See attached Kinds of U.S. Patent Documents. ³Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). ⁴For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. ⁵Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. ⁶Applicant is to place a check mark here if English language Translation is attached.



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Substitute for form 1449B/PTO INFORMATION DISCLOSURE STATEMENT BY APPLICANT <i>(use as many sheets as necessary)</i>				Complete if Known	
				Application Number	10/687,519
				Filing Date	10/16/2003
				First Named Inventor	Truskett et al.
				Group Art Unit	1762
				Examiner Name	Chen, Bret P.
Sheet	3	of	4	Attorney Docket Number	P75-17-03

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
	K6	Gokan et al., "Dry Etch Resistance of Organic Materials," J. Electrochem. Soc. 130:1, 143-146 (Jan. 1983)	
	K7	LIN, "Multi-Layer Resist Systems", Introduction of Microlithography," American Chemical Society, 1983, pp. 287-350, IBM T.J. Watson Research Center, Yorktown Heights, New York 10598.	
	K8	COWIE, "Polymers: Chemistry and Physics of Modern Materials," 1991, pp. 408-409, 2 nd Ed, Chapman and Hall, a division of Routledge, Chapman and Hall, Inc., 29 West 35 th Street, NY, NY 10001-2291.	
	K9	KRUG et al., "Fine Patterning of Thin Sol-Gel Films," Journal of Non-Crystalline Solids, 1992, pp. 447-450, vol. 147 & 148.	
	K10	Kotachi et al., "Si-Containing Positive Resist for ArF Excimer Laser Lithography," J. PhotopolymerSci. Tech. 8(4) 615-622, 1995.	
	K11	Krauss et al., "Fabrication of Nanodevices Using Sub-25nm Imprint Lithography," Appl. Phys. Lett 67(21), 3114-3116, 1995	
	K12	CHOU et al., "Imprint of Sub-25 nm Vias and Trenches in Polymers," Applied Physics Letters, November 20, 1995, pp. 3114-3116, vol. 67(21).	
	K13	CHOU et al., "Imprint Lithography with 25-Nanometer Resolution," Science, Apr. 5, 1996, pp. 85-87, vol. 272.	
	K14	HAISMA et al., "Mold-Assisted Nanolithography: A Process for Reliable Pattern Replication," Journal of Vacuum Science and Technology, Nov/Dec 1996, pp. 4124-4128, vol. B 14(6).	
	K15	CHOU et al., "Imprint Lithography with Sub-10nm Feature Size and High Throughput," Microelectronic Engineering, 1997, pp. 237-240, vol. 35.	
	K16	SCHEER et al., "Problems of the Nanoimprinting Technique for Nanometer Scale Pattern Definition," Journal of Vacuum Science and Technology, Nov/Dec 1998, pp. 3917-3921, vol. B 16(6).	

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				Application Number	10/687,519
				Filing Date	10/16/2003
				First Named Inventor	Truskett et al.
				Group Art Unit	1762
				Examiner Name	Chen, Bret P.
Sheet	4	of	4	Attorney Docket Number	P75-17-03

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
	K17	XIA et al., "Soft Lithography," Annu. Rev. Mater. Sci., 1998, pp. 153-184, vol. 28.	
	K18	XIA et al., "Soft Lithography," Agnew. Chem. Int. Ed., 1998, pp. 550-575, vol. 37.	
	K19	COLBURN. et al., "Step and Flash Imprint Lithography: A New Approach to High-Resolution Patterning", Proc. of SPIE, 1999, pp. 379-389, vol. 3676.	
	K20	CHOU et al., "Lithographically-Induced Self Assembly of Periodic Polymer Micropillar Arrays," Journal of Vacuum Science and Technology, Nov/Dec 1999, pp. 3197-3202, vol. B 17(6).	
	K21	CHOI et al., "Design of Orientation Stages for Step and Flash Imprint Lithography," Precision Engineering, Journal of the International Societies for Precision Engineering and Nanotechnology, 2001, pp. 192-199, vol. 25.	
	K22	CHOU, "Nanoimprint Lithography and Lithographically Induced Self-Assembly," MRS Bulletin, July 2001, pp. 512-517.	
	K23	Nguyen, A. Q., "Asymmetric Fluid-Structure Dynamics in Nanoscale Imprint Lithography," University of Texas at Austin, August 2001.	

Examiner Signature		Date Considered	
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